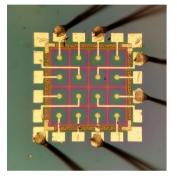
Development of (V)UV-Sensitive GaN Geiger-Mode Photodiodes



Minkyu Cho, Theeradetch Detchprohm, Russell Dupuis, Eliza Gazda, Hoon Jeong, Mi-Hee Ji, Marzieh Noodeh-Bakhtiary, Shyh-Chiang Shen, Zhiyu Xu



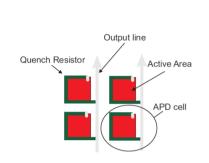


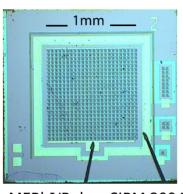
Nepomuk Otte

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Center for Relativistic Astrophysics



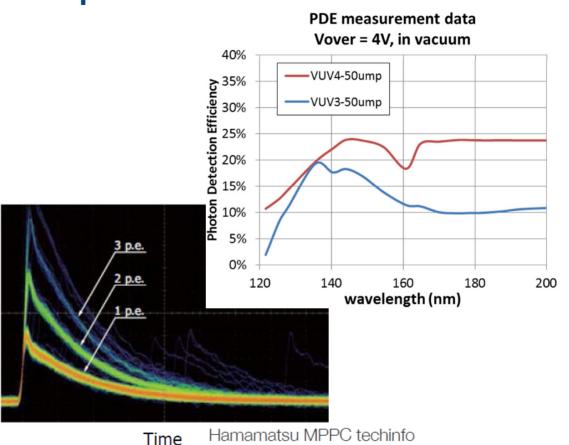
The Silicon Photomultiplier or G-APD





MEPhI/Pulsar SiPM 2004

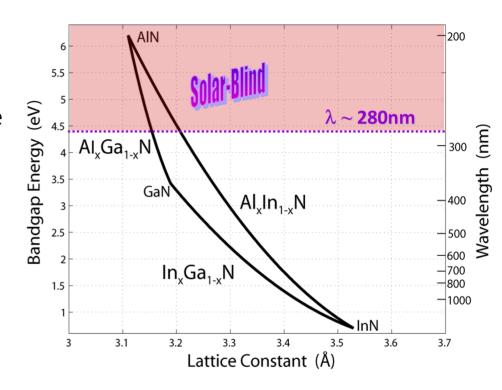
Pulse height



Can the SiPM concept be transferred to GaN?

Why GaN?

- Large bandgap
 - •Tunable bandgap -> tunable spectral response
 - Potential for high UV-VUV sensitivity with little to no red sensitivity
- Sufficiently clean substrates are available
 - Geiger-mode is possible
- Increasing use of GaN in high-power electronics, LEDs, Lasers
 - Increasing supply of GaN-substrates
 - Cleaner substrates
 - Lower cost



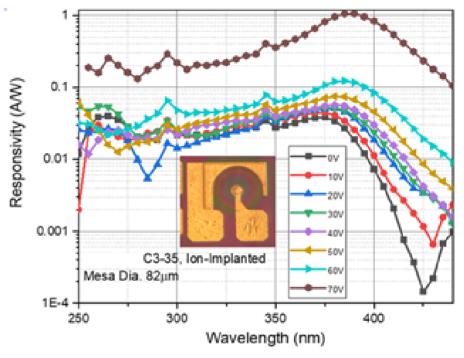
The GaN Technical and Intellectual Challenge

Geiger-mode in GaN is unexplored

- Breakdown probability?
- Temperature dependencies?
- •Electric field dependencies?
- •Quenching?

Device Fabrication

- Uniform breakdown characteristics
- •Low dark-count rates
- Scalability
- Arrays
- •...



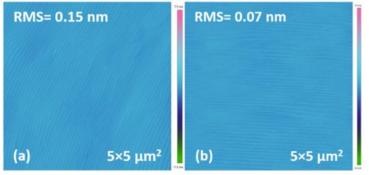
Spectral response of a 82 um-dia. Georgia Tech GaN APD

Georgia Tech GaN Structures

https://doi.org/10.1117/12.2576888

epitaxial growth

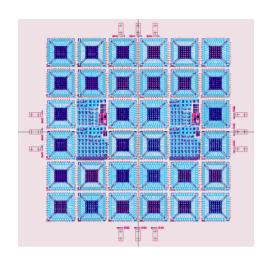
surface roughness:



20 nm p**-GaN:Mg 100 nm p-GaN:Mg ($p \sim 6 \times 10^{17}$ cm⁻³m) 200 nm u-GaN 1000 nm n-GaN:Si (n~7x1018 cm-3) SiOo Ni/Ag/Ni/Au p++-GaN:Mg **GaN Substrate** p-GaN:Ma u-GaN Ti/AI/Ti/Au Ti/Al/Ti/Au n-GaN:Si Avalanche region n-GaN Substrate

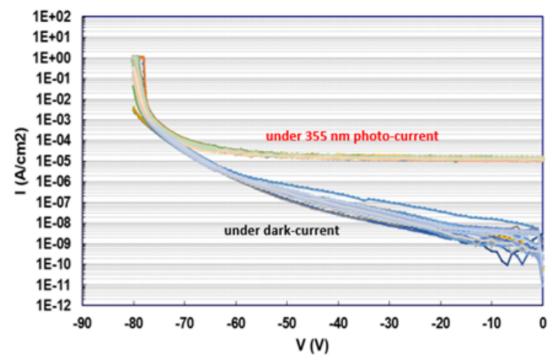
Growth on: u-GaN/sapphire n-GaN bulk substrate

IV-Curves



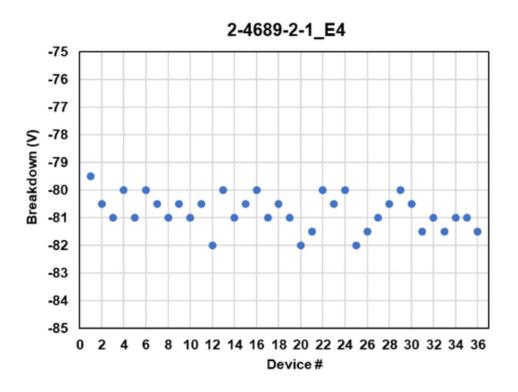
36 diode array of 60 um cells

- Uniform dark current characteristics
- Uniform light response



https://doi.org/10.1117/12.2576888

Breakdown Voltage Uniformity



Uniform breakdown characteristics (<1% variations)

Geiger Mode Measurements

Noninverting amplifier

New territory

-> Develop setups from scratch

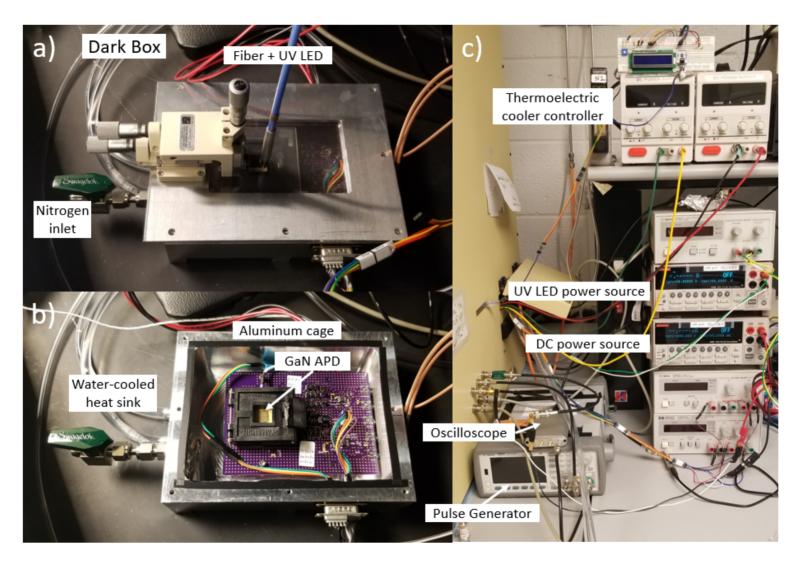
Ampl.: 7.5V width 1us

Freq. 1kHz

Pulse

b) bias pulse Δt Transimpedance dark-count breakdown ADA4817 GaN Oscilloscope

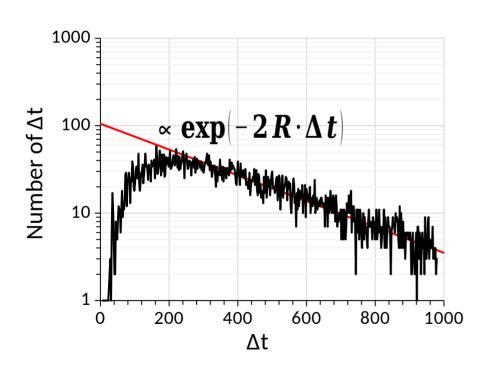
100nF

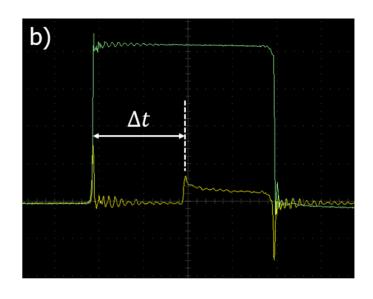


Nepomuk Otte

Count Rate Measurments

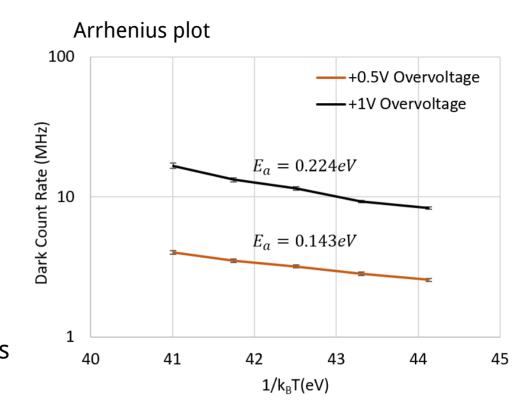
Determine count rate from Δt distribution





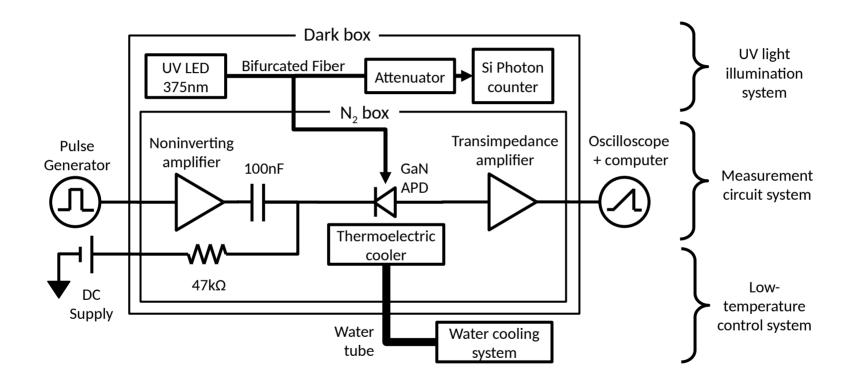
Dark-Count Rates

- Temperature range -10°C 10°C
- Overvoltages 0.5 V and 1 V
- Dark count rates (DCR) > 1MHz
- Activation energies ~0.2 eV ->
 DCR dominated by trap-assisted tunneling (Poole-Frenkel)
- Breakdown voltage shifts 0.02%/K (SiPMs 0.1%/K)

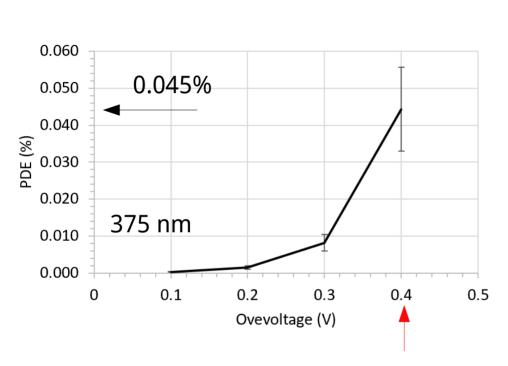


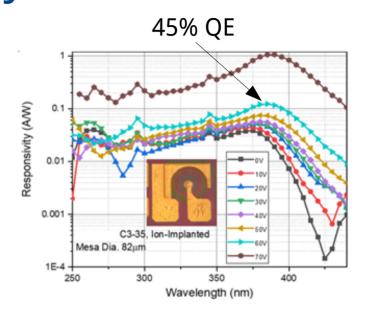
High dark-count rate prevents operation at higher overvoltages (cf. early SiPMs)

Photon Detection Efficiency: Setup



Photon Detection Efficiency



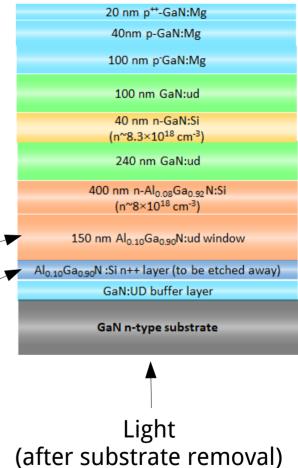


~0.1% breakdown probability at 0.4V overvoltage (~0.5% above breakdown voltage)

Operation at higher overvoltages will result in higher breakdown probabilities

Next Steps

- Reduce DCR -> Get rid of Poole-Frenkel tunneling
 - Impurity states in "intrinsic layer"
 - Residual crystalline defects
 - Growth studies have shown we can reduce "unintentional impurities" in the avalanche region
 - Employ low-defect III-N substrates
 - Further studies of ion-implantation
- AlGaN "window" for better UV sensitivity
- Back-side illumination designs
- Selective etching for substrate removal
- Provides for "flip-chip" mounting to Si bias/readout circuit



Summary

- •GaN G-APDs have the potential for high (V)UV sensitivity.
- •We succeeded in operating GaN diodes in Geiger mode.
 - •All things considered the results are very encouraging.
- •High DCR prevents operation at high breakdown probability.
 - Device can only operate <1% above breakdown -> latest SiPMs operate 10%-20% above breakdown -> lots of room for improvement.
 - •Identified trap assisted tunneling as dominant DCR mechanism.
- The situation is very similar to early silicon SPADs and SiPMs.
 - No fundamental limitations identified.
 - The same methodology that improved SiPM characteristics can also improve GaN.

Look forward to our next generation of GaN SPADs.